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Shrivastava

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(54) **DEVICE ISOLATORS**

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H01L 23/00 (2006.01)
H01L 49/02 (2006.01)

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(2013.01); **H01L 28/60** (2013.01); **H01L**
2224/04042 (2013.01); **H01L 2224/48137**
(2013.01)

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H01L 27/0794; H01L 27/0805; H01L
28/40; H01L 23/5222; H01L 23/5225;
H01L 23/5226; H01L 24/48; H01L
2224/48137

See application file for complete search history.

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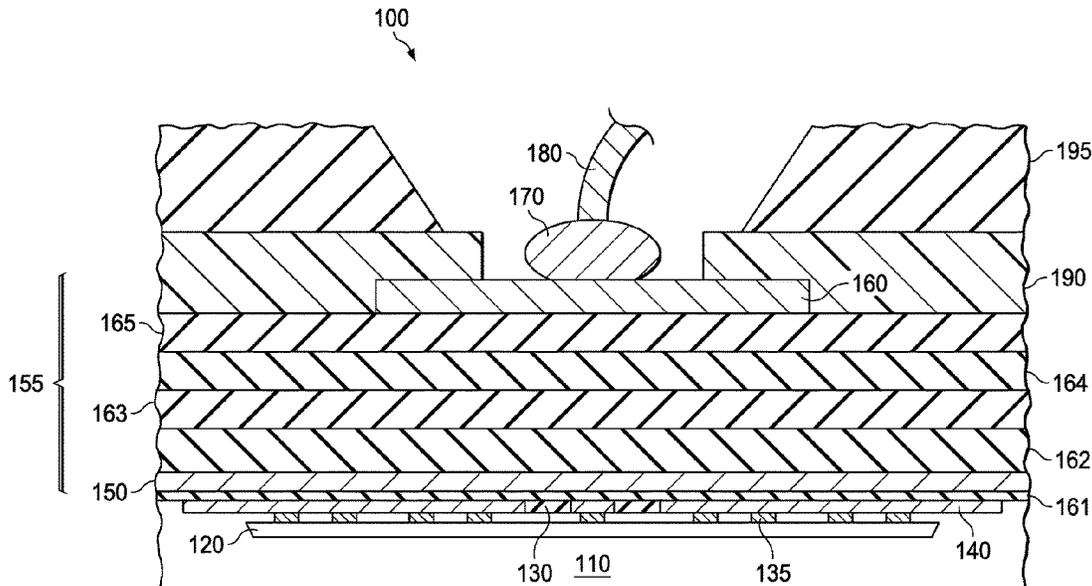
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D. Cimino

(57) **ABSTRACT**

An integrated semiconductor device having a metallic ele-
ment formed between a capacitor with and a doped region.

20 Claims, 7 Drawing Sheets



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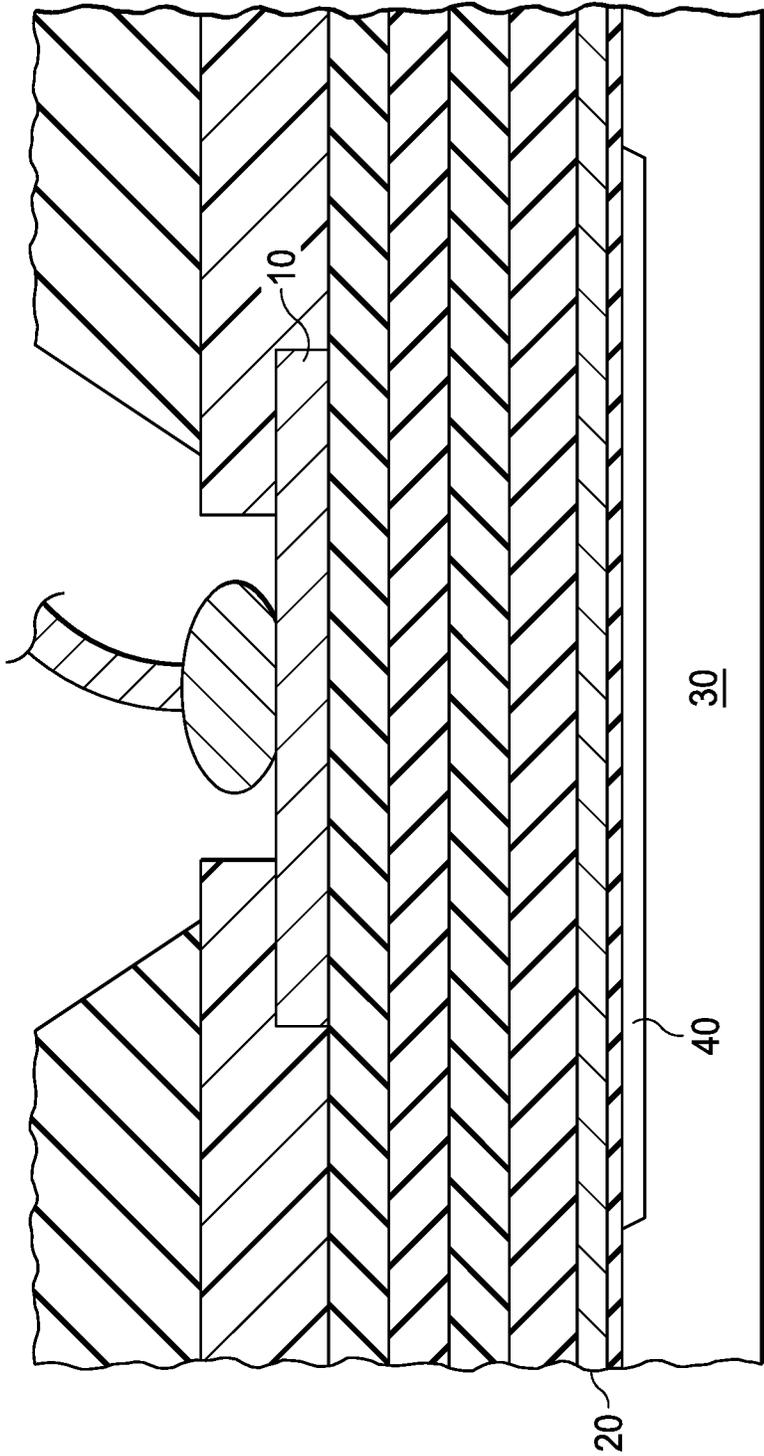


FIG. 1

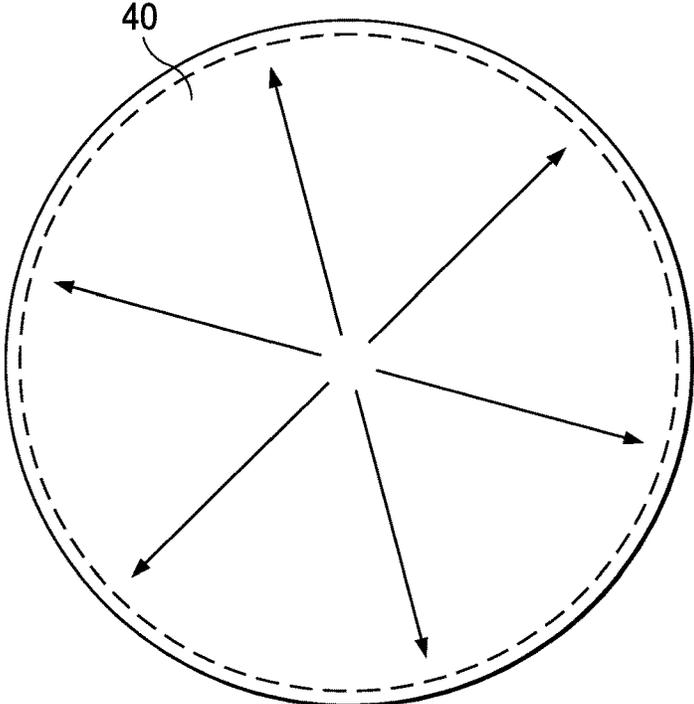


FIG. 2

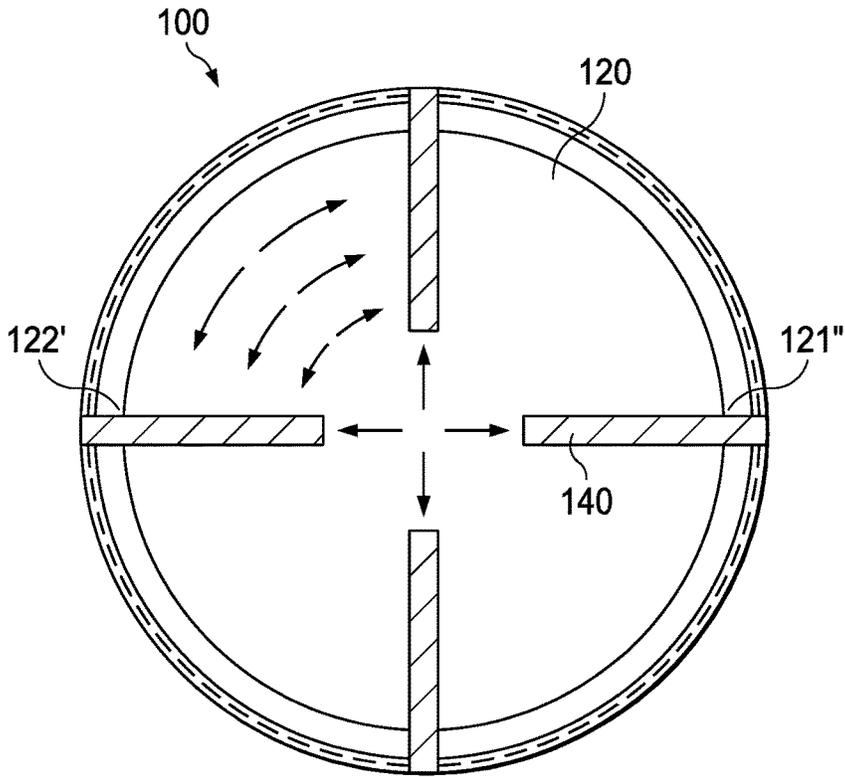


FIG. 4

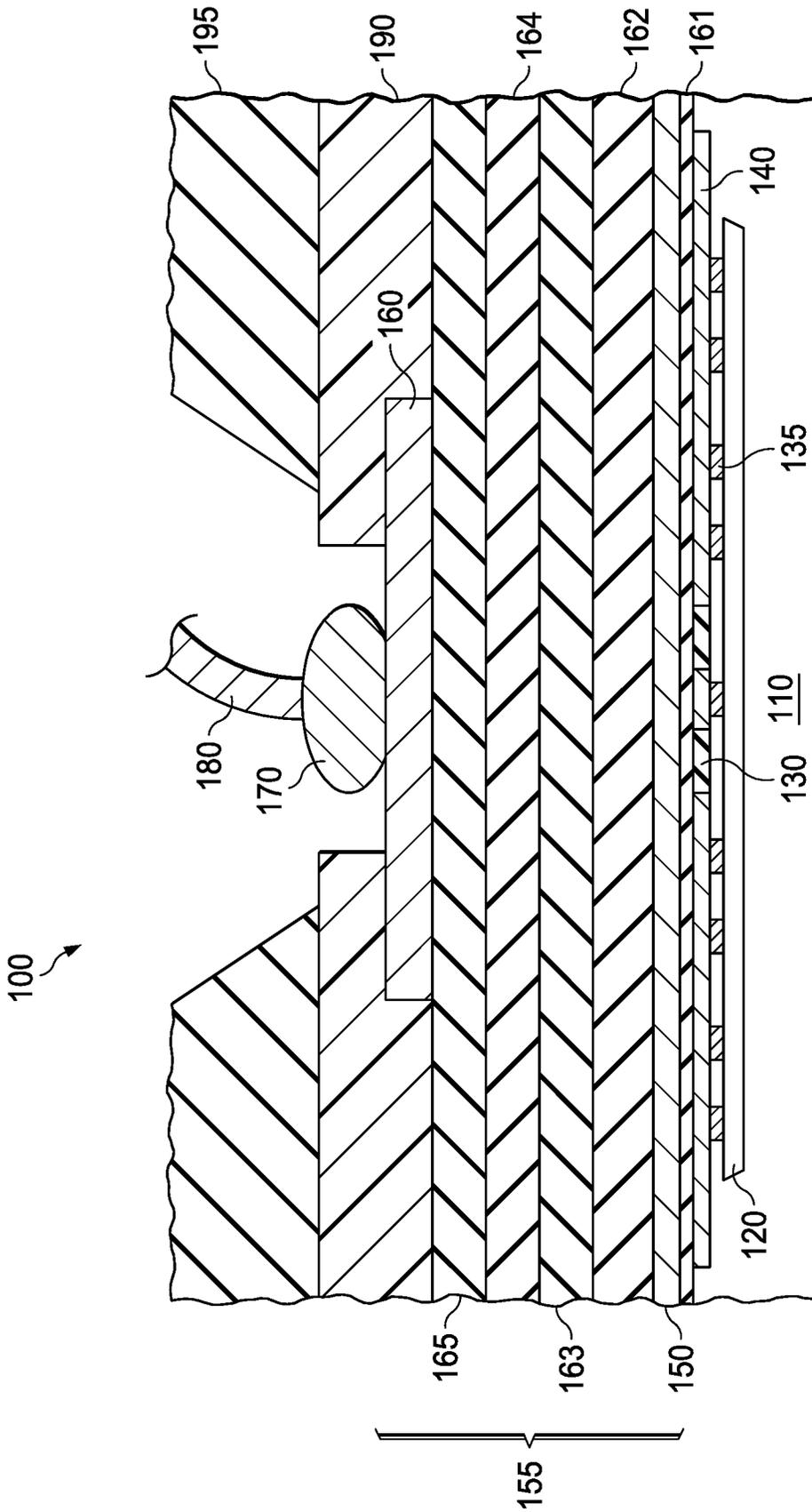
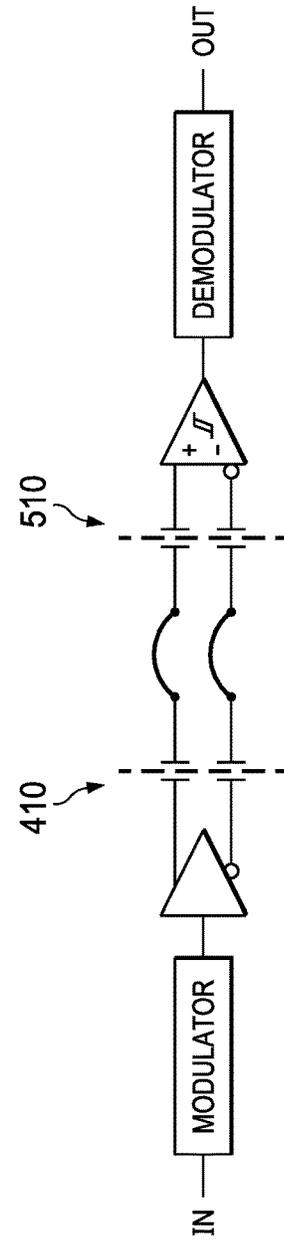
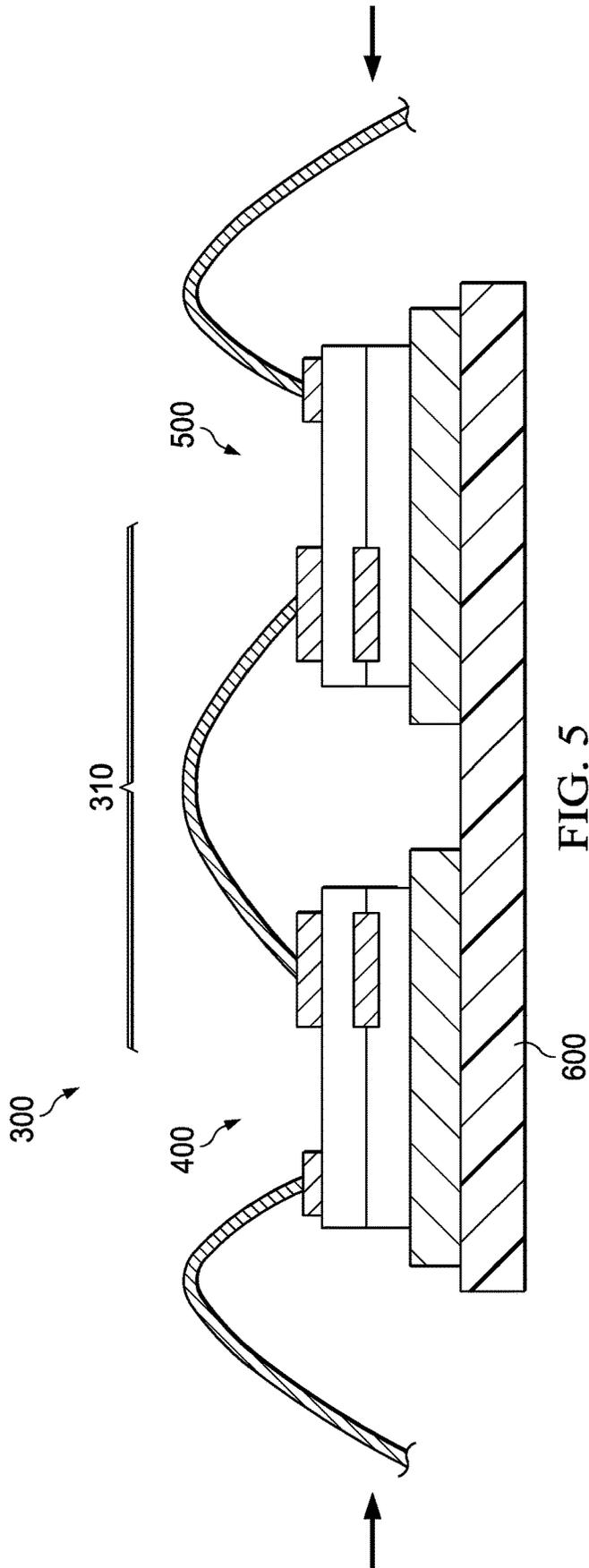


FIG. 3



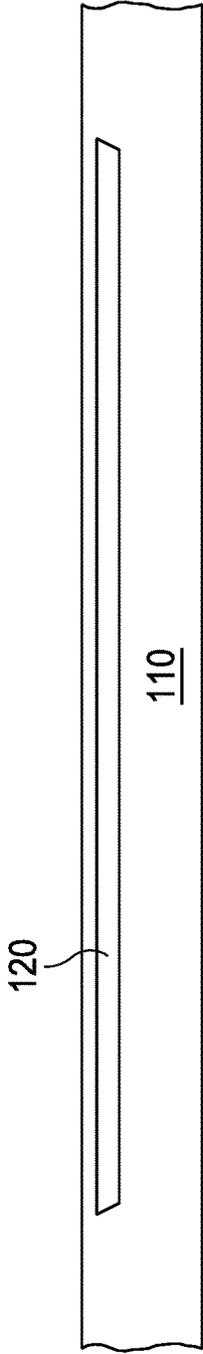


FIG. 7

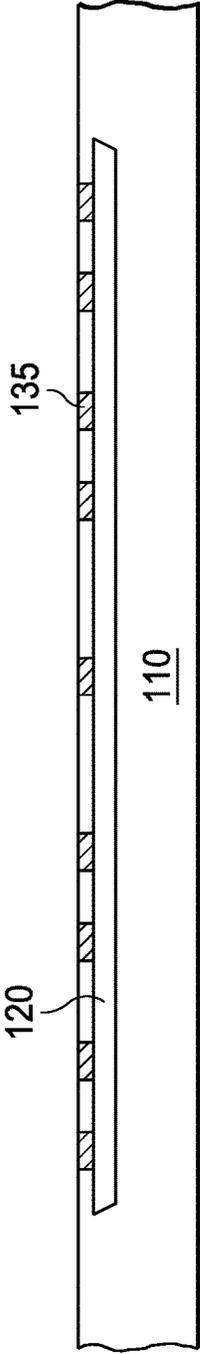


FIG. 8

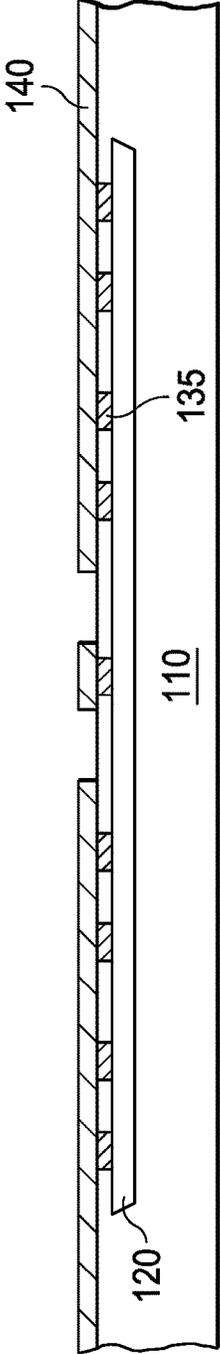


FIG. 9

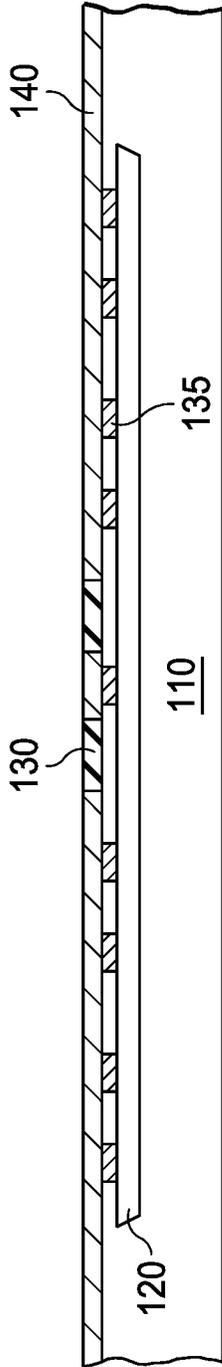


FIG. 10

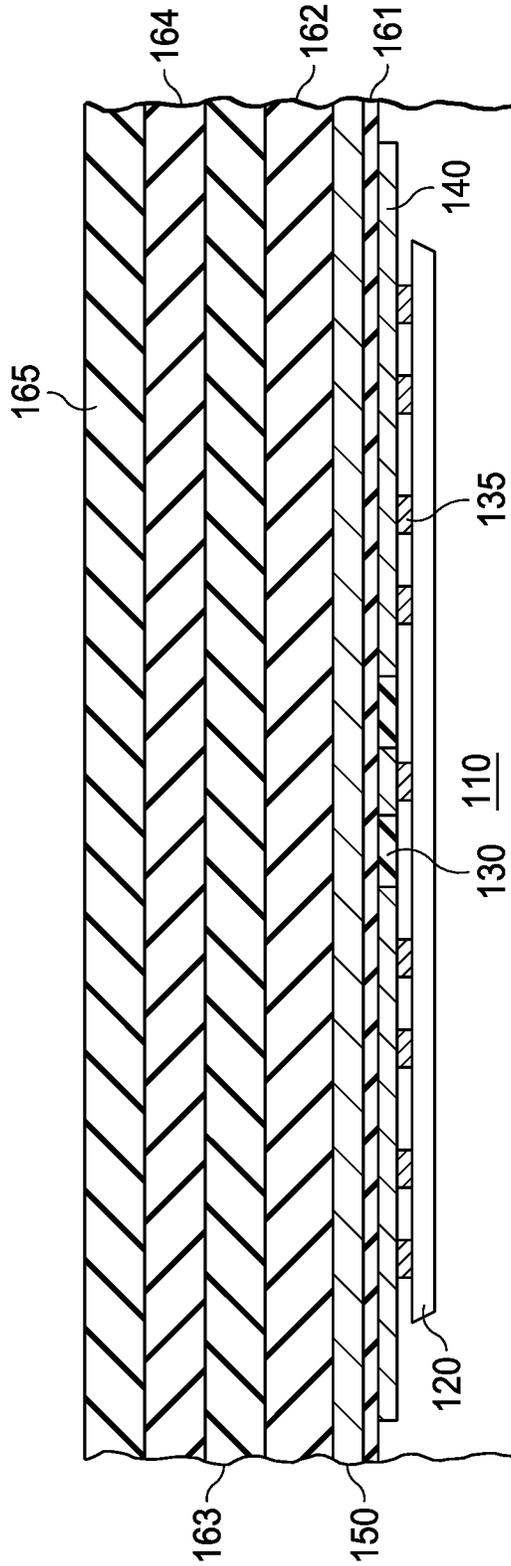


FIG. 11

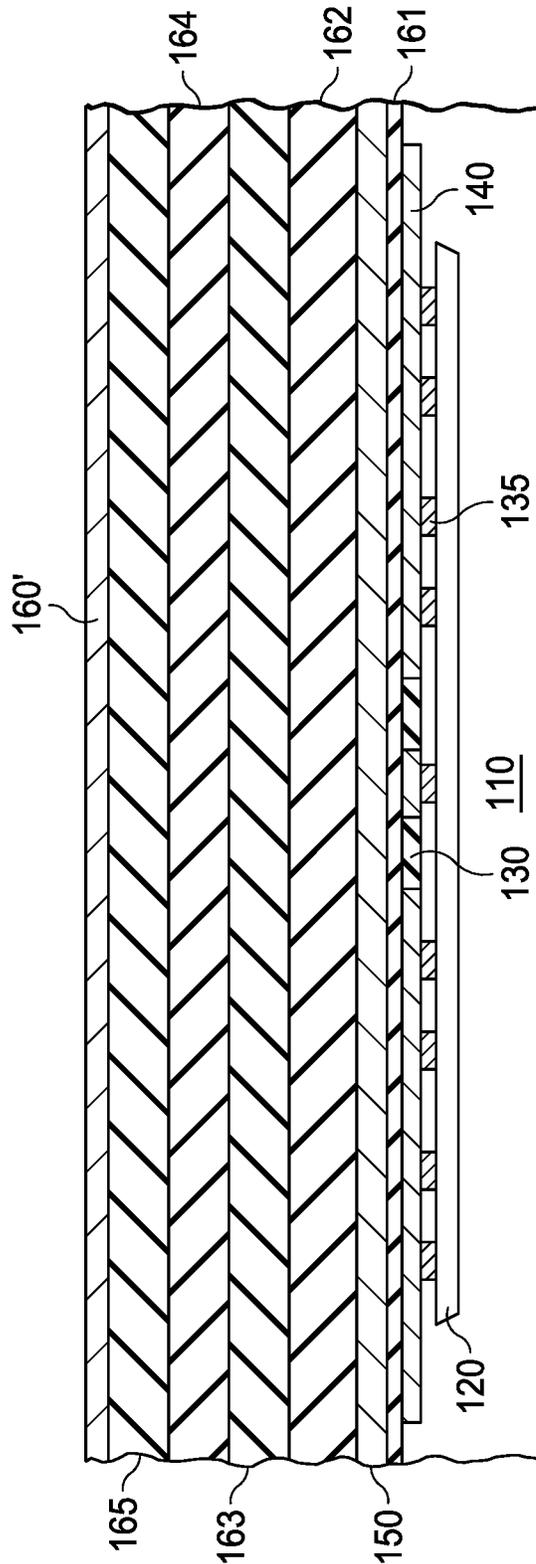


FIG. 12

DEVICE ISOLATORS

RELATED APPLICATION

This application claims the benefit of Indian Provisional Application No. 201941015751, filed on Apr. 20, 2019. The entire content of that application is hereby incorporated by reference.

BACKGROUND OF THE INVENTION AND RELATED ART

Aspects of the disclosure relate generally to device isolators. Conventional isolators are used to in many devices to isolate functional sections of electrical systems in order to prevent current flow between them but allow data to pass between two devices. This is typically done by capacitors having a top electrode **10** and a bottom electrode **20** formed over a substrate **30** having a doped region **40** as shown in FIG. **1** (a cross-sectional view of a flat bottom electrode within or over a doped well in a semiconductor substrate).

One of the drawbacks to the conventional isolator is that the path for any current within the doped region of the substrate to a node (such as a ground) is variable and can take any path along its surface as shown in FIG. **2**. This can result in parasitic capacitance, which lowers the quality factor (or Q) of the isolator. As such, an improved isolator is desired.

SUMMARY

An aspect of the present disclosure relates to an integrated device having an isolator having a substrate with a doped region and first, second, and third metallic elements formed over the substrate. An additional aspect of the present disclosure relates to an improved device isolator having a ten-fold quality factor (Q) than conventional device isolators.

BRIEF DESCRIPTION OF THE DRAWINGS

For a detailed description of various examples, reference will now be made to the accompanying drawings in which:

FIG. **1** illustrates a portion of a conventional isolator;

FIG. **2** illustrates a top-down view of a conventional flat bottom electrode formed either within or over a doped well in a semiconductor substrate;

FIG. **3** illustrates a partial cross-sectional view of a device isolator in accordance with an embodiment of the present disclosure;

FIG. **4** illustrates a partial top-down view of a second metallic element in accordance with an embodiment of the present disclosure;

FIG. **5** illustrates an integrated semiconductor device having a device isolator in accordance with an embodiment of the present disclosure;

FIG. **6** illustrates a schematic of an integrated semiconductor device having a device isolator in accordance with an embodiment of the present disclosure; and

FIGS. **7-12** illustrate an exemplary method of forming embodiments in accordance with the present disclosure.

DETAILED DESCRIPTION

Certain terms have been used throughout this description and claims to refer to particular system components. As one skilled in the art will appreciate, different parties may refer

to a component by different names. This document does not intend to distinguish between components that differ in name but not function. In this disclosure and claims, the terms “including” and “comprising” are used in an open-ended fashion, and thus should be interpreted to mean “including, but not limited to.” Also, the term “couple” or “couples” is intended to mean either an indirect or direct wired or wireless connection. Thus, if a first device couples to a second device, that connection may be through a direct connection or through an indirect connection via other devices and connections.

Aspects of the disclosure relate generally to integrated semiconductor devices having device isolators. As illustrated in FIG. **3**, which is a cross-sectional view of a portion of an isolator device **100** in accordance with the present disclosure, a substrate **110** having a doped region **120** formed therein has a series of contacts **135** coupling a plurality of first metallic elements **140** formed over the substrate **110** to the doped region **120**. The first metallic elements **140** are connected to a node (not shown). The node could be a ground. The first metallic elements **140** are separated from one another by an oxide layer **130**. The first metallic elements **140** comprise a non-continuous metallic layer separated by the oxide layer **130** that may serve as a ground for any current in the doped region **120**. The isolator device **100** also includes a second metallic element **150** that forms a bottom electrode of a capacitor **155** and a third metallic element **160** that forms the top electrode of the capacitor **155**. The capacitor **155** is formed above the first metallic elements **140**. Also shown are multiple inter-layer dielectric elements (first inter-layer dielectric element **161**, second inter-layer dielectric element **162**, third inter-layer dielectric element **163**, fourth inter-layer dielectric element **164**, and fifth inter-layer dielectric element **165**). Any one of the inter-layer dielectric elements could be formed of an oxide material. The isolator device **100** also includes a wire bond **170** that is coupled to a wire **180**. Also included are a protective overcoat **190** and a top inter-layer dielectric element **195**.

As shown in FIG. **4**, the first metallic elements **140** provide a shorter pathway (as indicated by the arrows) for any current in the doped region **120** of the substrate **110** to travel. As illustrated, the first metallic elements **140** are formed as metallic strips that extend outwardly from a center of the doped region **120**. Because the current is drawn away by shorter paths, the first metallic elements **140** are able to dissipate any parasitic resistivity quicker, which results in improved quality factor (Q) of nearly ten-fold as compared with conventional device isolators like the one shown in FIG. **1**. It should be noted that the example with four first metallic elements **140** is not intended to be limiting. For example, the isolator device **100** could have one first metallic element **140** formed as a strip that extends from a first edge of the doped region **120'** to a second edge of the doped region **120''** or could have less than four or greater than four first metallic elements **140**. The number of first metallic elements **140** depends on its intended application.

An integrated circuit device **300** incorporating the FIG. **3** structure is illustrated in FIG. **5**. As illustrated, a device isolator **310** can be used for communication from a first device **400** to a second device **500**. The two devices are optionally on or in a single package **600**. The example is not, however, intended to be limiting to such an arrangement. For example, the two devices may be on separate packages. The isolation is realized by using capacitors combined in series (FIG. **6**). Each channel uses high-voltage isolation capacitors on both first device **400** and second device **500**. As

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shown in the schematic cross-section in FIG. 6, the high-voltage pair of capacitors **410** and **510** are connected in series. The combined isolation capacitor thickness can vary, and typically should be greater than 21 microns. As shown in FIG. 6, data is transmitted across the isolation barrier. Signal comes in, is modulated, goes across the barrier as part of a differential pair of capacitors (**410** and **510**), demodulated, and out. This same isolation communication path is used for digital isolators, for isolated links, for A to D converters, isolated amplifiers, isolated gate drivers, and other integrated semiconductor devices.

It should also be noted that the integrated circuit **300** of FIGS. 5 and 6 should have at least one device having first metallic elements **140** formed between the doped region **120** and a capacitor **155**. But, depending on the intended application, not every device requires first metallic elements **140** formed between the doped region **120** and a capacitor **155**.

FIGS. 7-12 illustrate an exemplary embodiment of a method of forming a device isolator in accordance with the present disclosure. FIG. 7 illustrates a substrate **110** having a doped region **120** formed therein. Typically, the doped region **120** is a shallow n-type well (or SWELL). However, the doped region could be an n-type or s-type region depending on the application. FIG. 8 illustrates a plurality of contacts **135** formed over the doped region **120**. This can be accomplished by selectively etching portions of the substrate and depositing the etched portions with a metallic material.

FIG. 9 illustrates the formation of the first metallic elements **140** over the doped region **120**. The first metallic elements **140** can be formed by depositing a metallic precursor layer over the substrate **110** and plurality of contacts **135**, and selectively removing portions of the metallic precursor layer to form the first metallic elements **140**. The removal process can be performed by selectively etching portions of the metallic layer with or without the use of a mask.

FIG. 10 shows an oxide layer **130** formed to planarize the structure, and to separate the first metallic elements. The additional layers, including the second metallic element **150** and the inter-layer dielectric layers **161**, **162**, **163**, **164**, and **165**, that forms the bottom electrode of a capacitor **155** (FIG. 3.), are added to form the structure illustrated in FIG. 11. FIG. 12 shows a third metallic element precursor **160'** formed over the FIG. 11 structure. The third metallic element precursor **160'** is selectively removed to form the third metallic element **160** (FIG. 3), which forms the top electrode of capacitor **155** (FIG. 3). A protective overcoat **190** is formed over portions of the exposed inter-layer dielectric element **165** and selectively removed to expose a portion of the third metallic element **160** to which a wire bond **170** is formed (FIG. 3). A wire **180** is attached to the wire bond **170**.

The above discussion is meant to be illustrative of the principles and various embodiments of the present invention. Numerous variations and modifications will become apparent to those skilled in the art once the above disclosure is fully appreciated. For example, while the cross-sectional thicknesses of the various layers have been illustrated relative to one another in FIGS. 3-12, they are not intended to be limiting. Different relative thicknesses can be used. Accordingly, it is intended that the following claims be interpreted to embrace all such variations and modifications.

What is claimed is:

1. An integrated circuit, comprising:
 - a substrate;
 - a doped region within the substrate;

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first and second metallic elements over the doped region, the first and second metallic elements separated by an oxide region;

- a first metallic contact within the substrate and coupled directly between the first metallic element and the doped region, and a second metallic contact within the substrate and coupled directly between the second metallic element and the doped region; and
- a capacitor comprising:

- a third metallic element over the first and second metallic elements, and
- a fourth metallic element over the third metallic element.

2. The integrated circuit of claim 1, wherein the first metallic contact is configured to form a current path between the doped region and the first metallic element to draw current away from the doped region.

3. The integrated circuit of claim 2, wherein the second metallic contact is configured to form a current path between the doped region and the second metallic element to draw current away from the doped region.

4. The integrated circuit of claim 1, wherein the oxide region functions as a ground for current in the doped region.

5. The integrated circuit of claim 1, wherein the capacitor is a first capacitor, and the integrated circuit further comprising a second capacitor coupled to the first capacitor.

6. The integrated circuit of claim 1, wherein the first and second metallic elements are within the substrate.

7. An integrated circuit package having a plurality of semiconductor devices, at least one semiconductor device comprising:

- a substrate;
- a doped region within the substrate;
- first and second metallic elements over the doped region, the first and second metallic elements separated by an oxide layer;
- first and second metallic contacts within the substrate, the first metallic contact coupled directly between the first metallic element and the doped region, and the second metallic contact coupled directly between the second metallic element and the doped region; and

- a capacitor comprising:
 - a bottom electrode over the first and second metallic elements, and
 - a top electrode over the bottom electrode.

8. The integrated circuit of claim 7, wherein the first and second metallic elements are coupled to a ground.

9. The integrated circuit of claim 7, wherein the first and second metallic elements each extends outwardly from a center area of the doped region.

10. The integrated circuit of claim 7, wherein the first metallic contact is configured to form a current path between the doped region and the first metallic element to draw current away from the doped region, and the second metallic contact is configured to form a current path between the doped region and the second metallic element to draw current away from the doped region.

11. The integrated circuit of claim 7, wherein the first and second metallic elements are within the substrate.

12. An integrated circuit package having at least two semiconductor devices, each of the semiconductor devices comprising:

- a substrate;
- a doped region within the substrate;

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first and second metallic elements over the doped region, the first and second metallic elements separated by an oxide region;

first metallic contacts within the substrate and spaced apart and each having opposite sides and second metallic contacts within the substrate and spaced apart and each having opposite sides, the first metallic contacts contacting the first metallic element on one side and contacting the doped region on the other side, the second metallic contacts contacting the second metallic element on one side and contacting the doped region on the other side; and

a capacitor comprising:

- a first electrode over the first and second metallic elements, and
- a second electrode over the first electrode.

13. The integrated circuit of claim 12, wherein the first and second metallic elements are coupled to a ground.

14. The integrated circuit of claim 13, wherein the first and second metallic elements are strips of metallic material.

15. The integrated circuit of claim 14, wherein of the first and second metallic elements each extends outwardly from a center area of the doped region.

16. A method comprising:

- providing a substrate;
- forming a doped region within the substrate;
- forming metallic contacts within the substrate on the doped region;
- forming metallic elements on the metallic contacts;
- forming an oxide layer to separate the metallic elements from each other; and

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forming a capacitor comprising:

- depositing a first metallic layer over the metallic elements; and
- depositing a second metallic layer over the first metallic layer.

17. The method of claim 16, wherein each of the metallic elements is formed by depositing a metallic precursor layer on the metallic contacts and selectively removing portions of the metallic precursor layer.

18. The method of claim 16, wherein the metallic elements are formed as metallic strips that extend outwardly from a center area of the doped region.

19. A method of making an integrated circuit package having a substrate and a doped region within the substrate, the method comprising:

- forming metallic contacts within the substrate and on the doped region;
- forming metallic elements on the metallic contacts;
- forming an oxide layer to separate the metallic elements from each other; and
- forming a capacitor comprising:

- depositing a first metallic layer over the metallic elements; and
- depositing a second metallic layer over the first metallic layer.

20. The method of claim 19, wherein each of the metallic elements is formed by depositing a metallic precursor layer on the metallic contacts and selectively removing portions of the metallic precursor layer.

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